



2019 Facilities Day Open House

Tuesday, May 21
University of Wisconsin–Madison
Mechanical Engineering Building

AGENDA

8:00	Coffee/Breakfast	
8:30	Overview (Jerry Hunter, UW-Madison WCNT)	
	Microscopy Techniques	Microanalysis
9:00	<u>Scanning Electron Microscopy & EDS (60 min)</u> John Kelly, Zeiss <u>User Applications (15 min)</u> Speakers TBD	<u>Optical Spectroscopy (60 min)</u> Nolan Wong, Horiba Instruments <u>User applications (15 min)</u> Speakers, TBD
10:15	Break	
10:30	<u>Transmission Electron Microscopy (60 min)</u> Paul Voyles, UW-Madison MSE <u>Cryoelectron Microscopy (30 min)</u> Elizabeth Wright, UW-Madison Biochemistry <u>User Applications (15 min)</u> Speakers TBD	<u>Surface Analysis (XPS and Auger) (45 min)</u> Jerry Hunter, UW-Madison WCNT <u>User Applications (15 min)</u> Speakers TBD <u>Nanoindentation (30 min)</u> Julie Morasch, UW-Madison WCNT <u>User Applications (15 min)</u> Speakers TBD
12:15	Lunch	
1:15	<u>Focused Ion Beam (45 min)</u> Jerry Hunter, UW-Madison WCNT <u>User Applications (15 min)</u> Speakers TBD	<u>Rheometry and Dynamic Mechanical Analysis (45 min)</u> TA Instruments <u>User Applications (15 min)</u> Speakers TBD
2:15	<u>X-ray Analysis Methods (XRD, XRR, etc.) (45 min)</u> Don Savage, UW-Madison WCNT	<u>Basics of Nanoscale Fabrication (45 min)</u> Dan Christensen, UW-Madison WCNT
3:00	Break	
3:15	<u>Scanned Probe Microscopy (45 min)</u> John Thornton, Bruker <u>User Applications (15 min)</u> Sean Foradori, UW-Madison	<u>Metrology for Compound Semiconductors (45 min)</u> Dietrich von Diemar, Toho Technology <u>User Applications (15 min)</u> Speakers TBD
	Wrap Up (Jerry Hunter, UW-Madison WCNT)	
4:30	Tutorials End	